

In re Application of:  
Wang, et al.

Group Art Unit: 1765


Examiner: Maki A. Angadi

## For: Method Of Depositing An Amorphous Carbon Film For Metal Etch Hardmask Application

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being electronically transmitted to the U.S. Patent and Trademark Office via EFS-Web to the attention of Examiner Maki A. Angadi, on the date shown below.

Date 3/6/07

  
Keith M. Tackett

Dear Sir:

**SUBSTITUTE RESPONSE TO OFFICE ACTION DATED NOVEMBER 27, 2006**

In response to the Office Action dated November 27, 2006, having a shortened statutory period for response set to expire on February 27, 2007, please enter this substitute response replacing the response filed February 27, 2007, and reconsider the claims pending in the application for the reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.